

CPC**COOPERATIVE PATENT CLASSIFICATION****G01Q****SCANNING-PROBE TECHNIQUES OR APPARATUS;
APPLICATIONS OF SCANNING-PROBE TECHNIQUES, e.g.
SCANNING PROBE MICROSCOPY [SPM]****NOTE**

In this subclass, the first place priority rule is applied, i.e. at each hierarchical level, classification is made in the first appropriate place.

G01Q 10/00**Scanning or positioning arrangements, i.e. arrangements for actively controlling the movement or position of the probe**

G01Q 10/02

- . Coarse scanning or positioning

G01Q 10/04

- . Fine scanning or positioning

G01Q 10/045

- . . {Self-actuating probes, i.e. wherein the actuating means for driving are part of the probe itself, e.g. piezoelectric means on a cantilever probe}

G01Q 10/06

- . . Circuits or algorithms therefor

G01Q 10/065

- . . . {Feedback mechanisms, i.e. wherein the signal for driving the probe is modified by a signal coming from the probe itself}

G01Q 20/00**Monitoring the movement or position of the probe**

G01Q 20/02

- . by optical means

G01Q 20/04

- . Self-detecting probes, i.e. wherein the probe itself generates a signal representative of its position, e.g. piezo-electric gauge

G01Q 30/00**Auxiliary means serving to assist or improve the scanning probe techniques or apparatus, e.g. display or data processing devices**

G01Q 30/02

- . Non-SPM analysing devices, e.g. SEM [Scanning Electron Microscope], spectrometer or optical microscope

G01Q 30/025

- . . {Optical microscopes coupled with SPM}

G01Q 30/04

- . Display or data processing devices

G01Q 30/06

- . . for error compensation

G01Q 30/08

- . Means for establishing or regulating a desired environmental condition within a sample chamber

G01Q 30/10

- . . Thermal environment

G01Q 30/12

- . . Fluid environment

G01Q 30/14

- . . . Liquid environment

G01Q 30/16

- . . Vacuum environment

G01Q 30/18

- . Means for protecting or isolating the interior of a sample chamber from external environmental conditions or influences, e.g. vibrations or electromagnetic fields

G01Q 30/20

- . Sample handling device or method

G01Q 40/00**Calibration, e.g. of probes**

G01Q 40/02

- . Calibration standards and methods of fabrication thereof

G01Q 60/00	Particular type of SPM [Scanning Probe Microscopy] or microscopes; Essential components thereof
G01Q 60/02	. Multiple-type SPM, i.e. involving more than one SPM technique
G01Q 60/04	. . STM [Scanning Tunnelling Microscopy] combined with AFM [Atomic Force Microscopy]
G01Q 60/06	. . SNOM [Scanning Near-field Optical Microscopy] combined with AFM [Atomic Force Microscopy]
G01Q 60/08	. . MFM [Magnetic Force Microscopy] combined with AFM [Atomic Force Microscopy]
G01Q 60/10	. STM [Scanning Tunnelling Microscopy] or apparatus therefor, e.g. STM probes
G01Q 60/12	. . STS [Scanning Tunnelling Spectroscopy]
G01Q 60/14	. . STP [Scanning Tunnelling Potentiometry]
G01Q 60/16	. . Probes, their manufacture, or their related instrumentation, e.g. holders
G01Q 60/18	. SNOM [Scanning Near-Field Optical Microscopy] or apparatus therefor, e.g. SNOM probes
G01Q 60/20	. . Fluorescence
G01Q 60/22	. . Probes, their manufacture, or their related instrumentation, e.g. holders
G01Q 60/24	. AFM [Atomic Force Microscopy] or apparatus therefor, e.g. AFM probes
G01Q 60/26	. . Friction force microscopy
G01Q 60/28	. . Adhesion force microscopy
G01Q 60/30	. . Scanning potential microscopy
G01Q 60/32	. . AC mode
G01Q 60/34	. . . Tapping mode
G01Q 60/36	. . DC mode
G01Q 60/363	. . . {Contact-mode AFM}
G01Q 60/366	. . . {Nanoindenters, i.e. wherein the indenting force is measured}
G01Q 60/38	. . Probes, their manufacture, or their related instrumentation, e.g. holders
G01Q 60/40	. . . Conductive probes
G01Q 60/42	. . . Functionalization
G01Q 60/44	. SICM [Scanning Ion-Conductance Microscopy] or apparatus therefor, e.g. SICM probes
G01Q 60/46	. SCM [Scanning Capacitance Microscopy] or apparatus therefor, e.g. SCM probes
G01Q 60/48	. . Probes, their manufacture, or their related instrumentation, e.g. holders
G01Q 60/50	. MFM [Magnetic Force Microscopy] or apparatus therefor, e.g. MFM probes
G01Q 60/52	. . Resonance
G01Q 60/54	. . Probes, their manufacture, or their related instrumentation, e.g. holders
G01Q 60/56	. . . Probes with magnetic coating
G01Q 60/58	. SThM [Scanning Thermal Microscopy] or apparatus therefor, e.g. SThM probes
G01Q 60/60	. SECM [Scanning Electro-Chemical Microscopy] or apparatus therefor, e.g. SECM probes

G01Q 70/00	General aspects of SPM probes, their manufacture or their related instrumentation, insofar as they are not specially adapted to a single SPM technique covered by group G01Q 60/00
G01Q 70/02	. Probe holders
G01Q 70/04	. . with compensation for temperature or vibration induced errors
G01Q 70/06	. Probe tip arrays
G01Q 70/08	. Probe characteristics
G01Q 70/10	. . Shape or taper
G01Q 70/12	. . . Nano-tube tips
G01Q 70/14	. . Particular materials
G01Q 70/16	. Probe manufacture
G01Q 70/18	. . Functionalization
G01Q 80/00	Applications, other than SPM, of scanning-probe techniques (manufacture or treatment of nano-structures B82B 3/00 ; recording or reproducing information using near-field interaction G11B 9/12, G11B 11/24, G11B 13/08)
G01Q 90/00	Scanning-probe techniques or apparatus not otherwise provided for